

Power scaling of picosecond thin disc laser for LPP and FEL EUV sources

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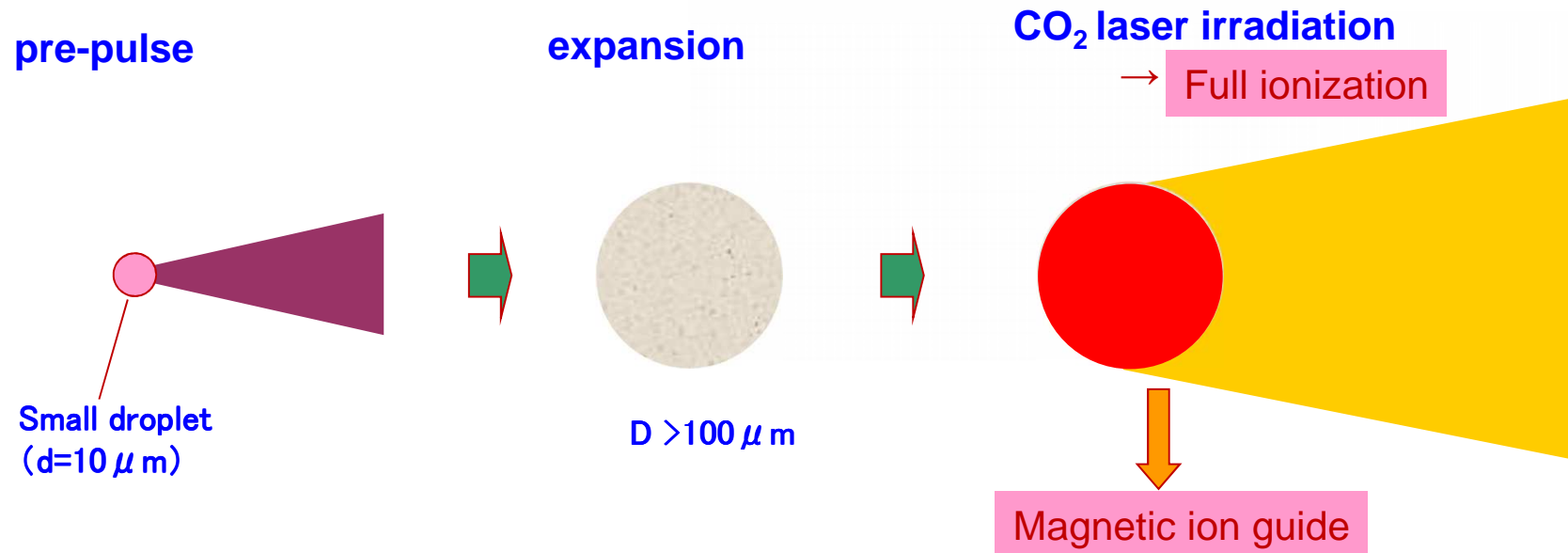
2) RISE, Waseda University, Tokyo, Japan

2016 International Workshop on EUV and Soft X-ray Sources
November 7-9, 2016 Amsterdam, The Netherlands

Subjects

1. LPP EUV source and high repetition rate picosecond laser
2. FEL EUV source and high average power tunable picosecond laser
3. Single shot laser Compton X-ray source for Bioimaging and high pulse energy picosecond laser
4. Solution:Thin disc laser and Cryogenic laser

Optimization of pre-plasma conditioning



*Optimize density, temperature and spatial distribution
for main pulse heating to achieve high EUV conversion efficiency*

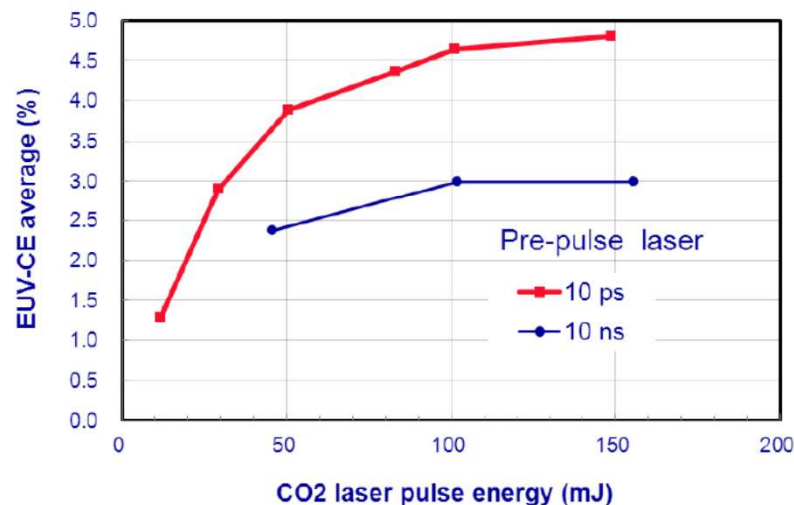
and full exhaust of Sn atoms : Beam quality is essential for higher CE

Mist tin bunch formation

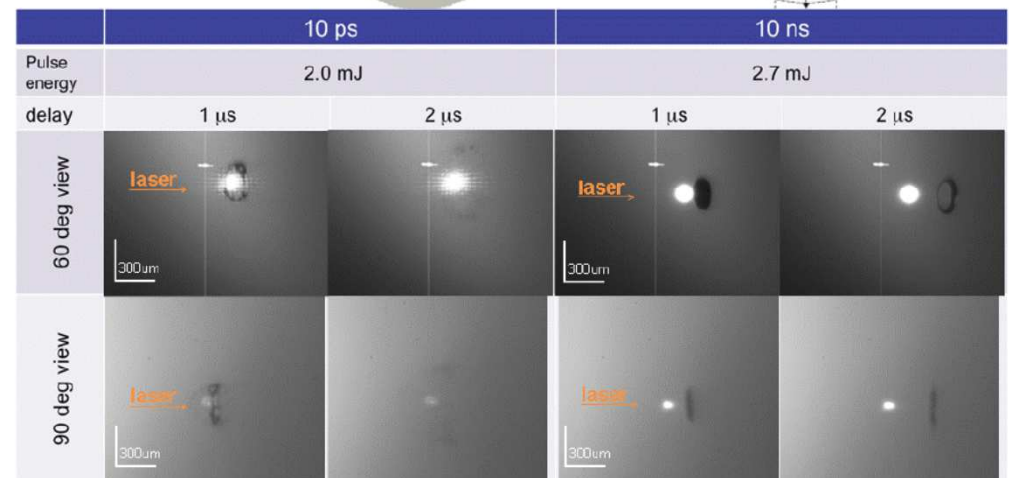
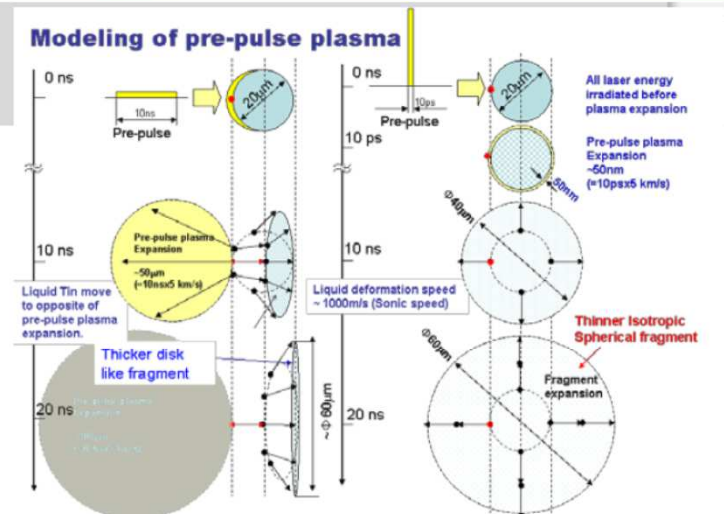
③ Pico-second Pre-Pulse Technology (1)

- The mist shape of a picosecond pre-pulse is different from the nanosecond
- Nano-cluster distribution could be a key factor for high CE
- Champion data was 4.7% (in 2012).

CO2 pulse energy vs. EUV-CE



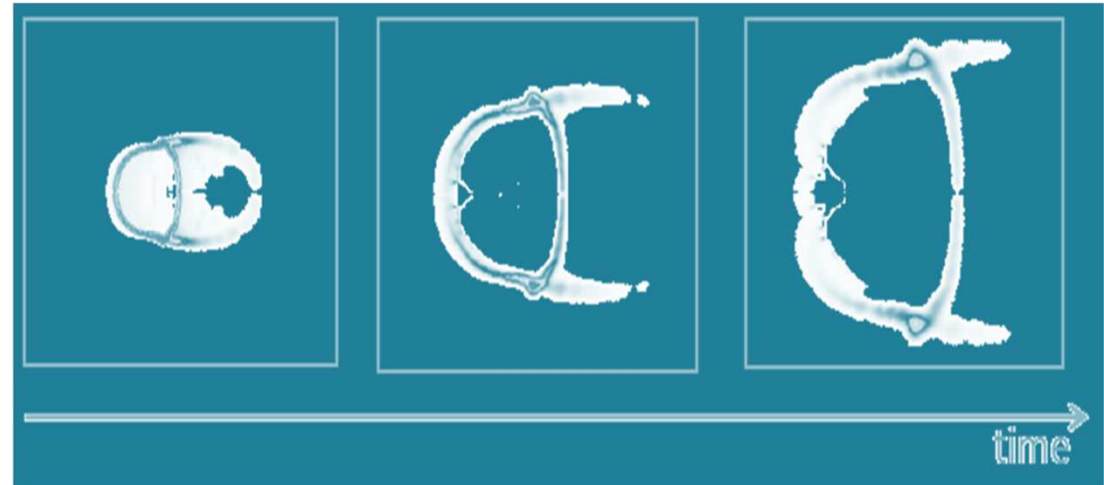
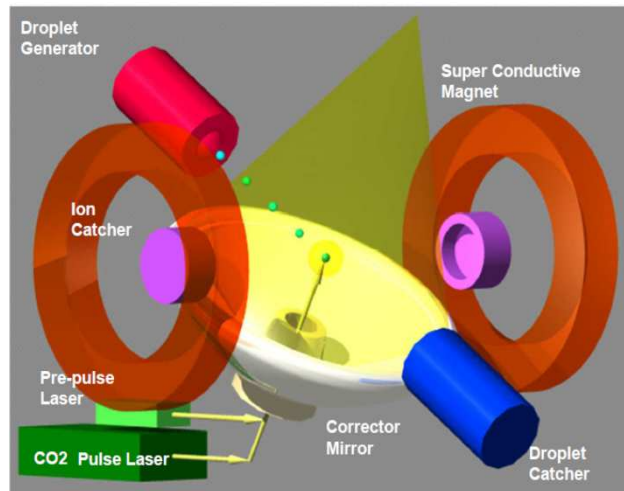
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SPIE Advanced Lithography 2016

February 23, 2016

Hollow Shell formation by picosecond pre-pulse



Time history of Sn nanocluster Hollow Shell formation

Configuration of LPP EUV source with picosecond pre-pulse

“Experimental and theoretical studies of tin droplets shaping by picosecond laser pre-pulses” (S24)

International Workshop on EUV and Soft X-ray Sources

November 9-11, Dublin, Ireland

Slava Medvedev et al, EUV Labs, Russia

Proposal : ERL (Energy Recovery Linac) FEL for >kW 13.5nm source

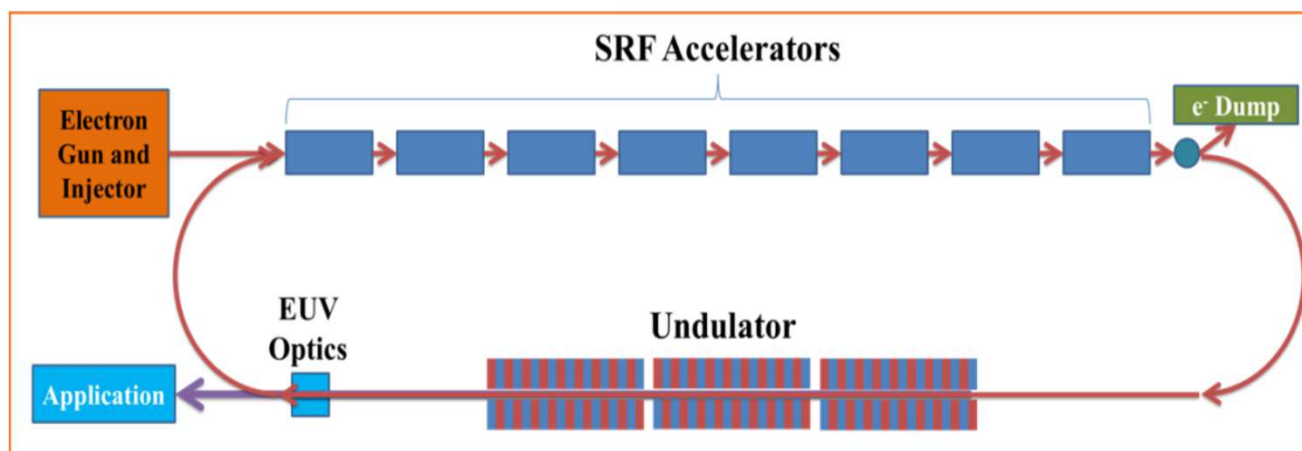


Waseda University



Power of light

From "Free-electron laser extreme ultraviolet lithography: considerations for high-volume manufacturing, Erik R. Hosler" presented at SPIE Advanced Lithography 2015



(\$M)		10x 250 W LPP Sources	EUV ERL FEL (10x Scanners Powered @ 1 kW)
Cost to Power 10 Scanners	OpEx	85	23
	CapEx	256	240
	Total Cost First Year	>341	263
	FEL CapEx Savings		16
	FEL Yearly OpEx Savings		62
Uptime Per Source		Target 90%	~100%
Average Exposures Per Day (10 Scanners, Dose: 25 mJ/cm ² , 120 Fields)		13,280	29,700



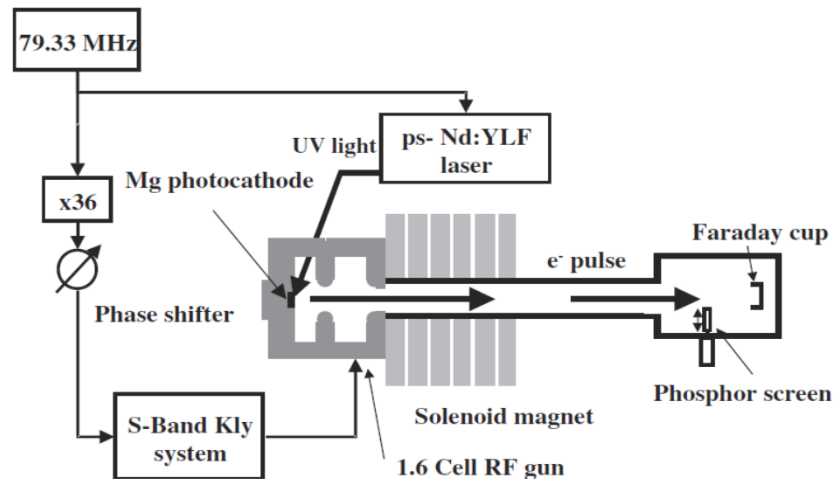


Fig. 3. Schematic diagram of the Mg cathode performance test system.

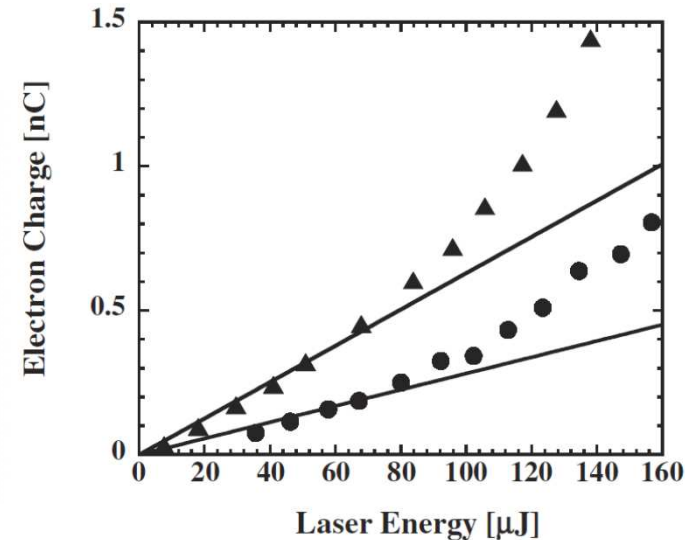


Fig. 5. Emitted electron charge from the Mg cathode as a function of the laser (349 nm) energy before (●) and after (▲) laser cleaning. The lines represent the best fit of the data at the laser energy <80 μJ.

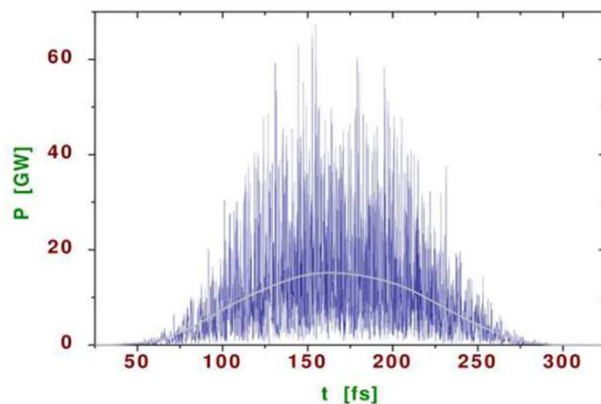
100μJ x 1MHz = 100W, several ps at 3HG

Jpn. J. Appl. Phys. Vol. 42 (2003) pp. 1470–1474
Part 1, No. 3, March 2003
©2003 The Japan Society of Applied Physics

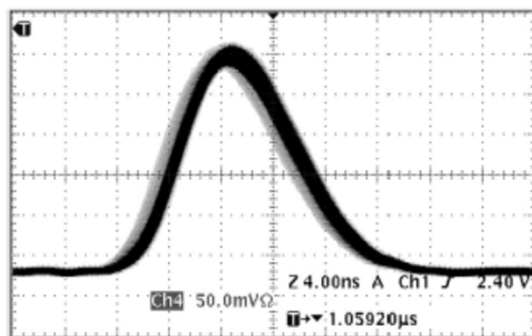
Quantum Efficiencies of Mg Photocathode under Illumination with 3rd and 4th Harmonics Nd:LiYF₄ Laser Light in RF Gun

Terunobu NAKAJYO, Jinfeng YANG, Fumio SAKAI and Yasushi AOKI

Temporal smoothing of FEL pulses by UV picosecond laser seeded HGHG

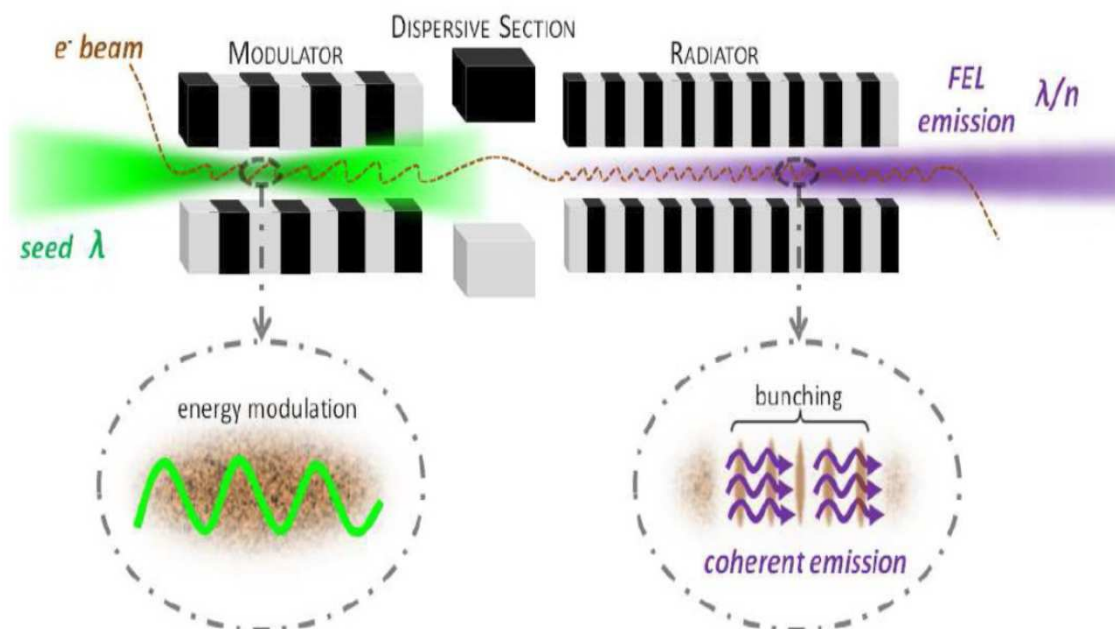


SASE FEL pulse shape



Smoothed pulse shape

$$100\mu\text{J} \times 10\text{MHz} = \text{kW}, 1\text{ps}, 4\text{HG}$$



Schematic of the working principle of a HGHG free-electron laser.

Chirped pulse amplification in X-ray free electron lasers
Hugo Ducasa et.al. SPIE 9585-15, San Diego 2015

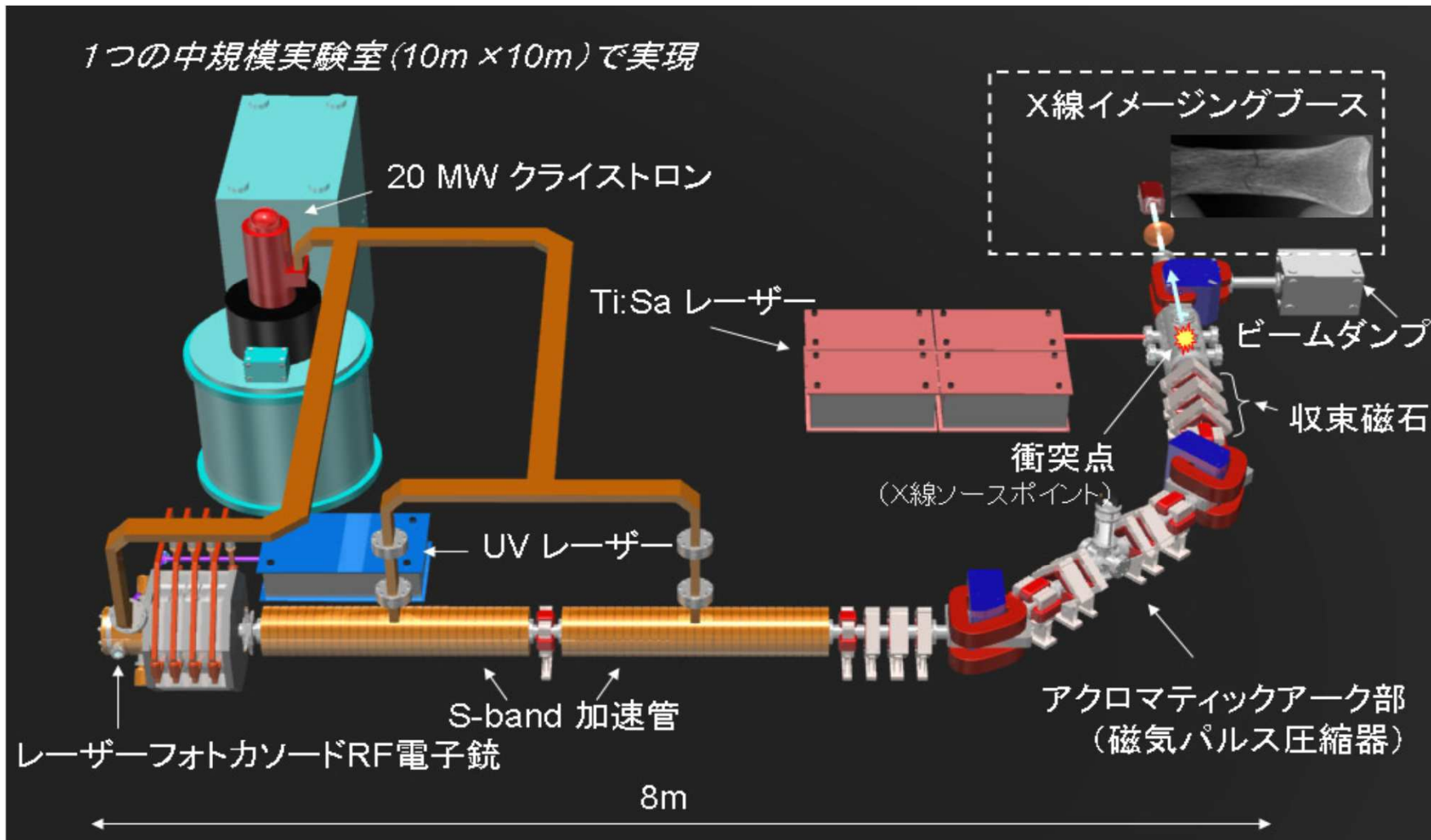
Single shot bio imaging by laser Compton X-ray source



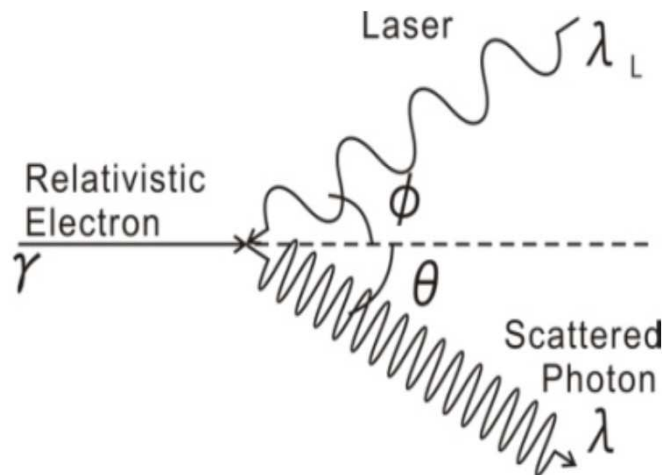
Waseda University



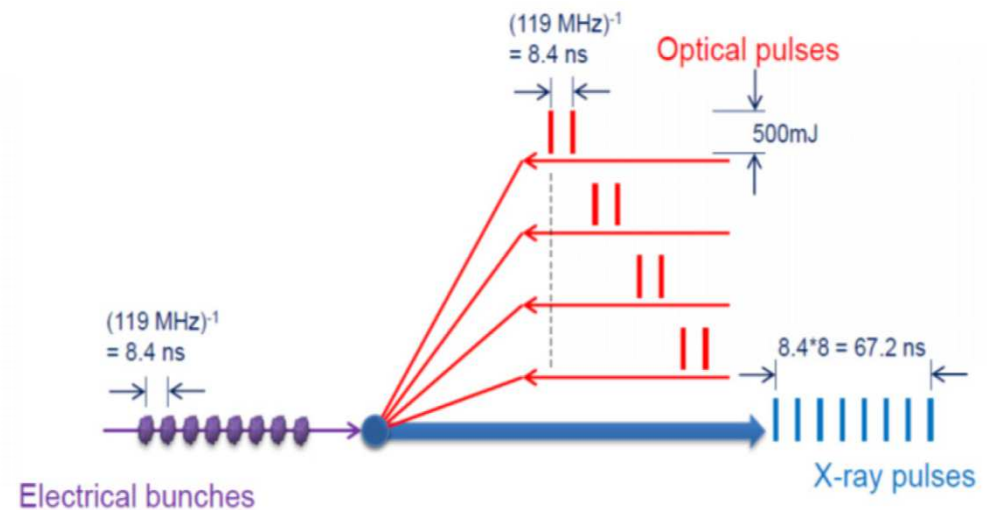
Power of light



Temporal spatial multiplexing of medium energy laser pulses for single shot imaging



Laser Compton configuration



Temporal-spatial multiplexing

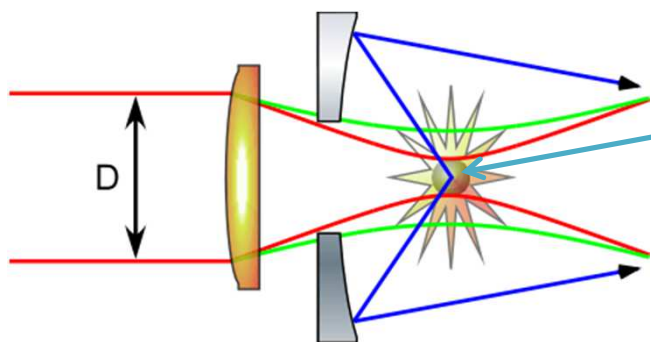
$$N_0 \propto \frac{\sigma_c N_e N_p}{4\pi r^2}$$

$R=10\mu\text{m}$ in single focus

X-ray photon number

Module pulse energy	>500mJ/ps
Module number	8 units
Multiplexed energy	4 J
Micro pulse time interval	8.4ns (119MHz)
Macro pulse width	~60ns

Focusing Property of Laser and M^2



Target size: $\phi 10\mu\text{m}$

Target size: $10\mu\text{m}$

Focal length of lens: $f=100\text{mm}$

• $D=20\text{mm}$

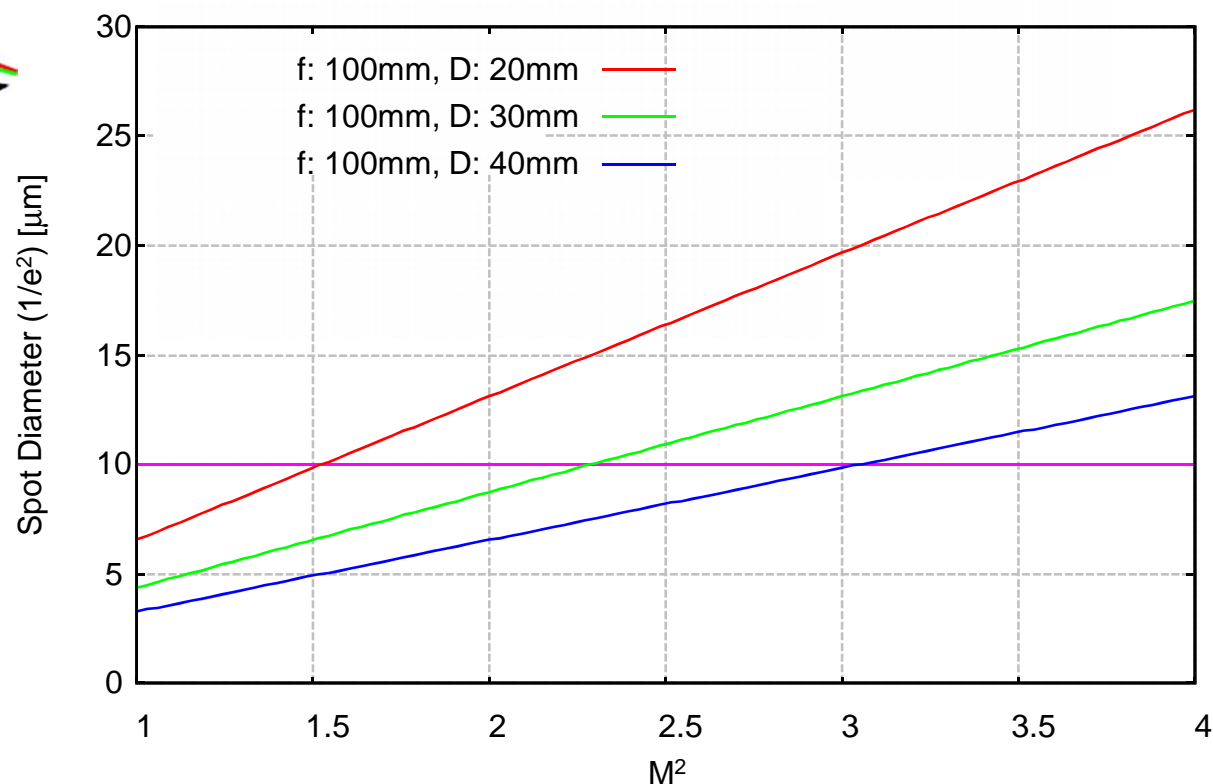
$M^2 < 1.5$

• $D=30\text{mm}$

$M^2 < 2.3$

• $D=40\text{mm}$

$M^2 < 3$

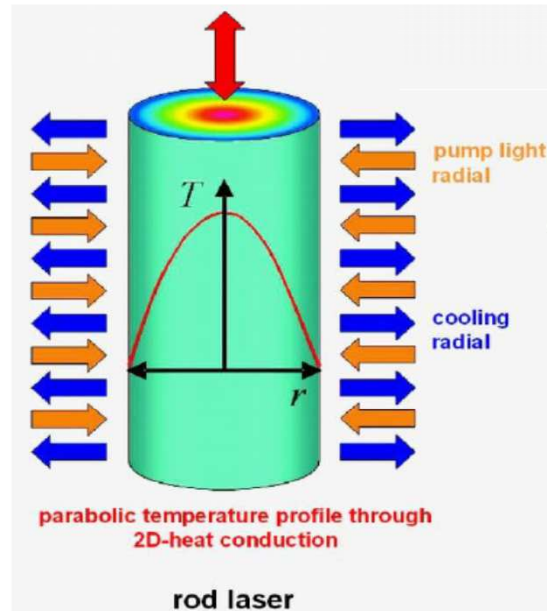


Configuration of solid state lasers for efficient cooling

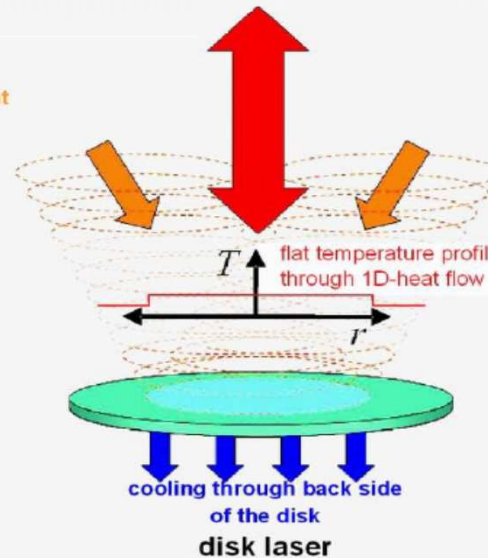
From presentation by Jonathan Tyler Green, ELI

Efficient cooling in SS lasers

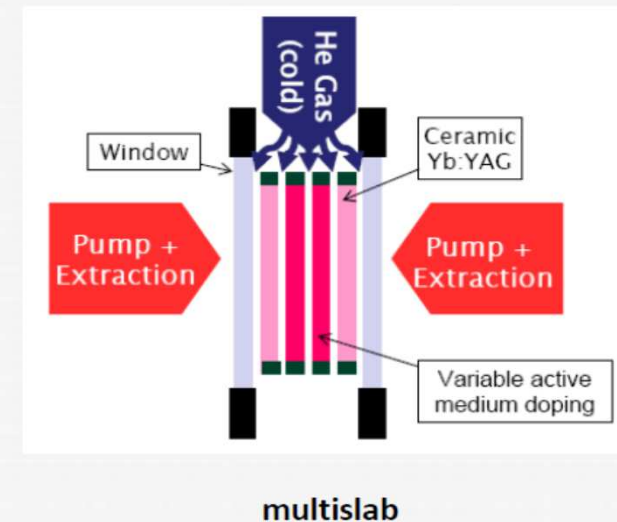
10 Hz rep. rates
Pulse energy 10J



kHz rep. rates
kW average power



10 Hz rep. rate
High pulse energy >100J



Courtesy T. Metzger (MPQ Garching)

Courtesy K. Ertel and J. Collier (RAL/STFC)

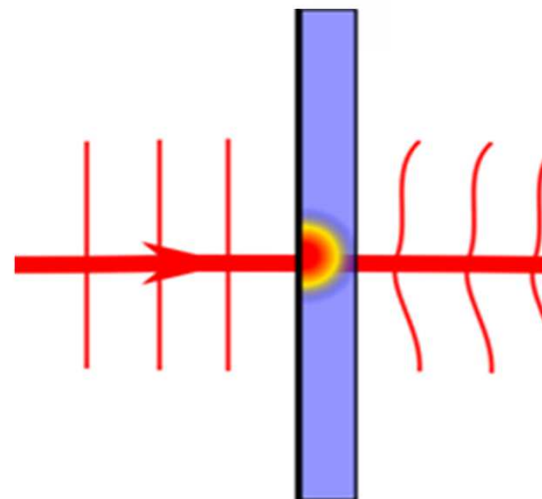
Wavefront distortion in solid state laser amplifier

Optical path difference (OPD)

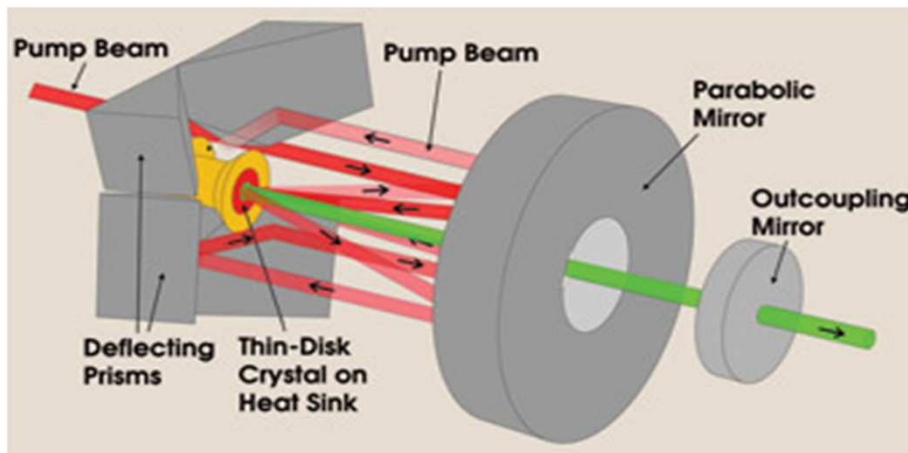
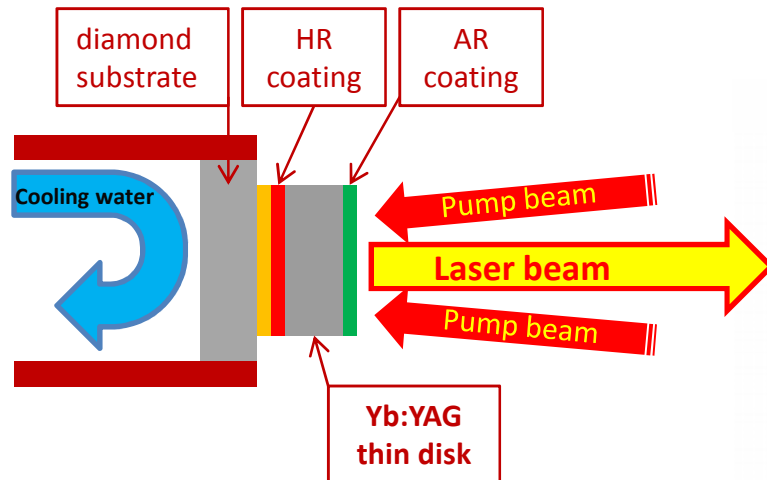
Opto-mechanical parameters Temperature field

$$\text{OPD} = \left[\frac{\partial n}{\partial T} + \alpha(1 + \nu)(n + 1) \right] \cdot \int_{z=0}^d \Delta T(x, y, z) dz$$

Thermo-optic coefficient Thermal expansion coefficient Poisson coefficient Refraction index



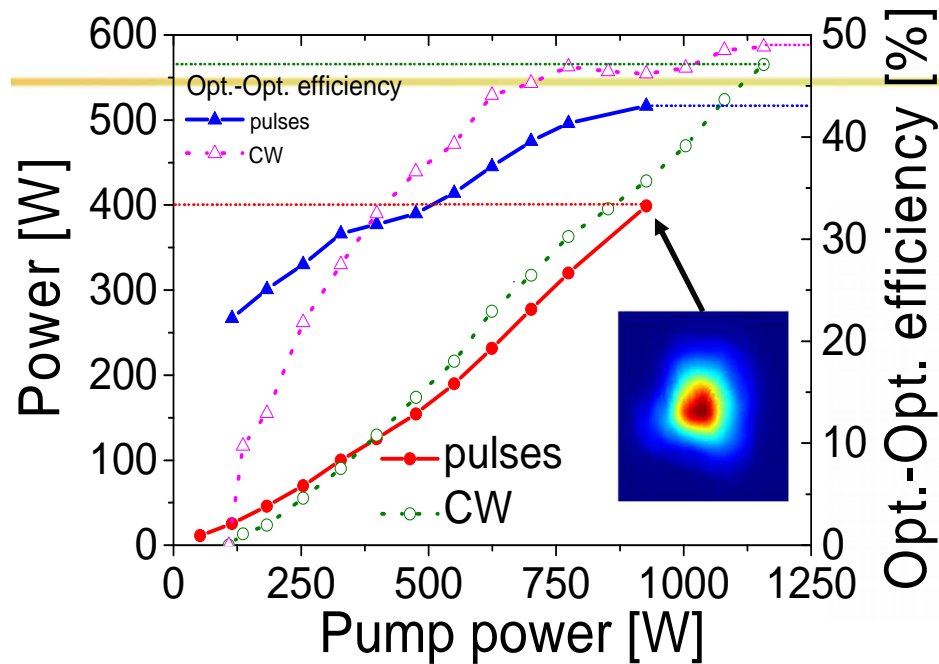
Yb:YAG thin-disks for high average power amplifiers



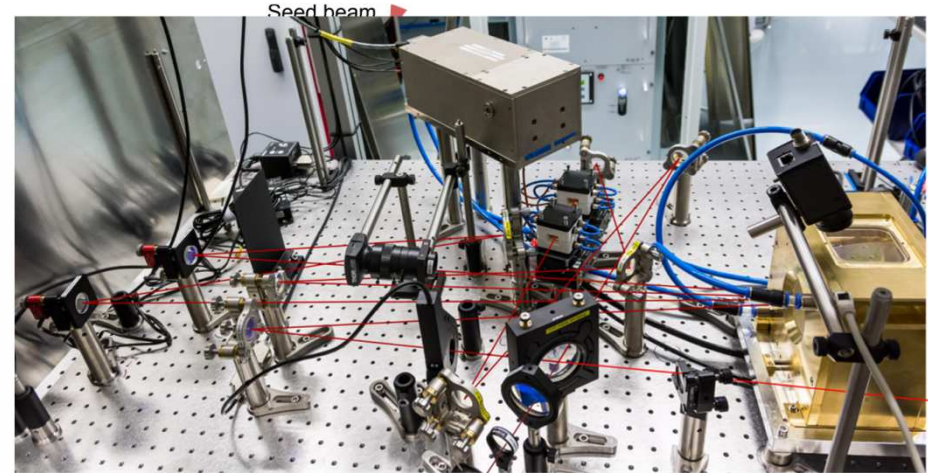
Thin disk parameters:

- 220 μm thickness
- 10 mm diameter
- 7.2 at.% Yb^{3+} doping
- water-cooled
- radius of curvature 3.9 m, increases under intense pumping - careful cavity design
- low gain \rightarrow regenerative amplifier

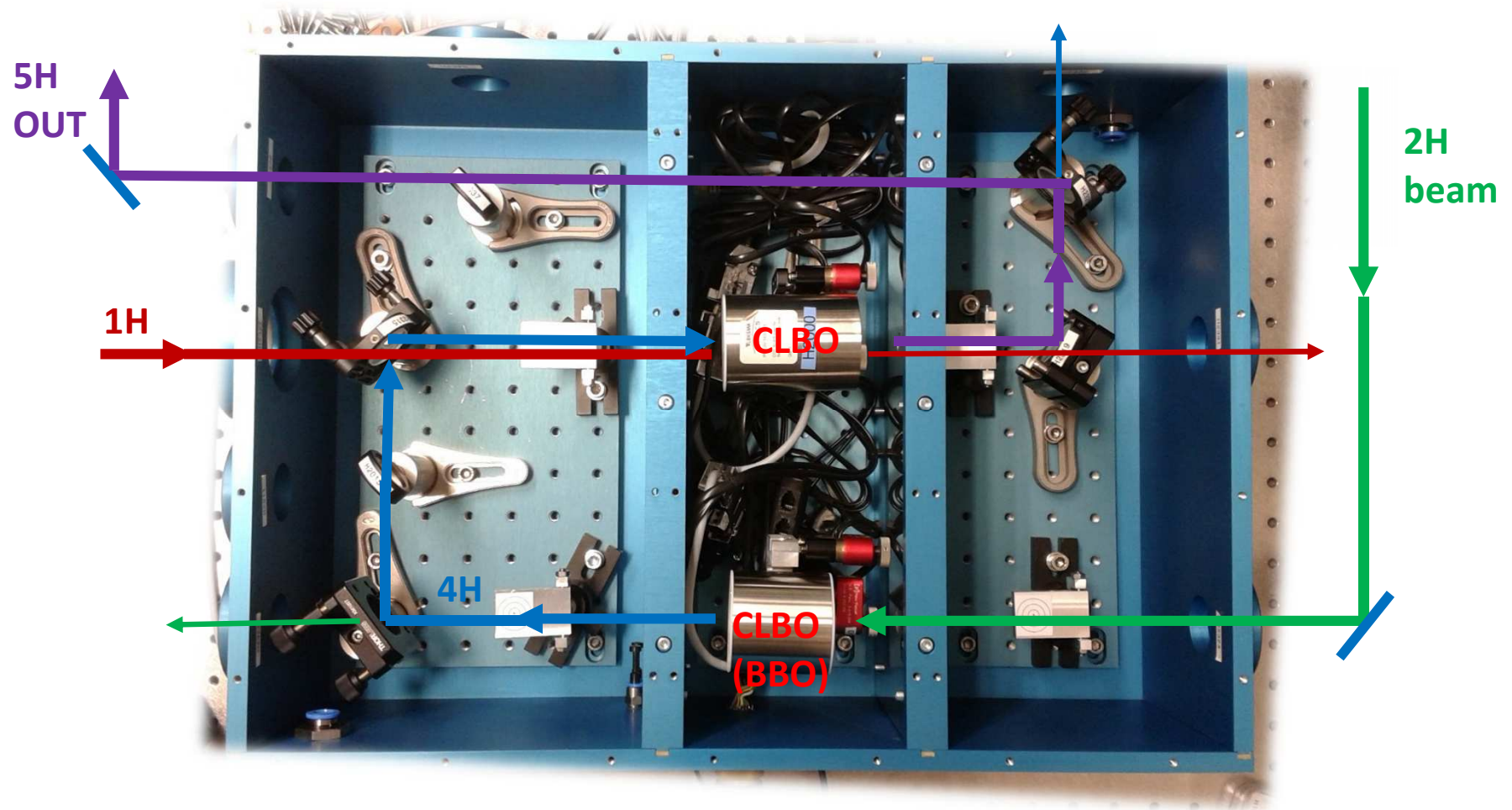




- Output energy 4 mJ at 100 kHz
- >0.5 kW in CW mode
- High opt. efficiency >43% in pulse mode
- Good beam quality M^2 1.3 and 1.4 in x, y
- BBO Pockels cell (2x 10x10x24mm BBO)
- In-house development of components (PC holder, compressor, cooled mirrors, laser head to 50 W)

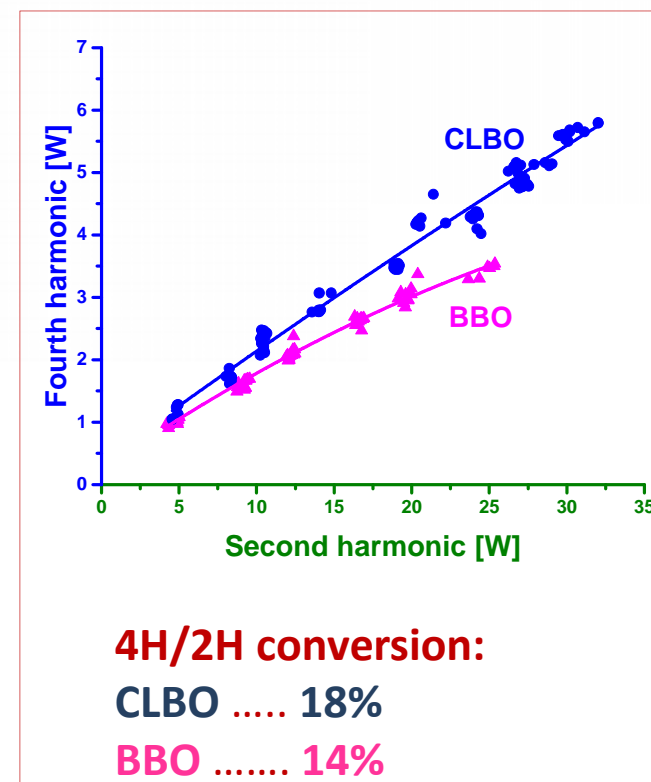
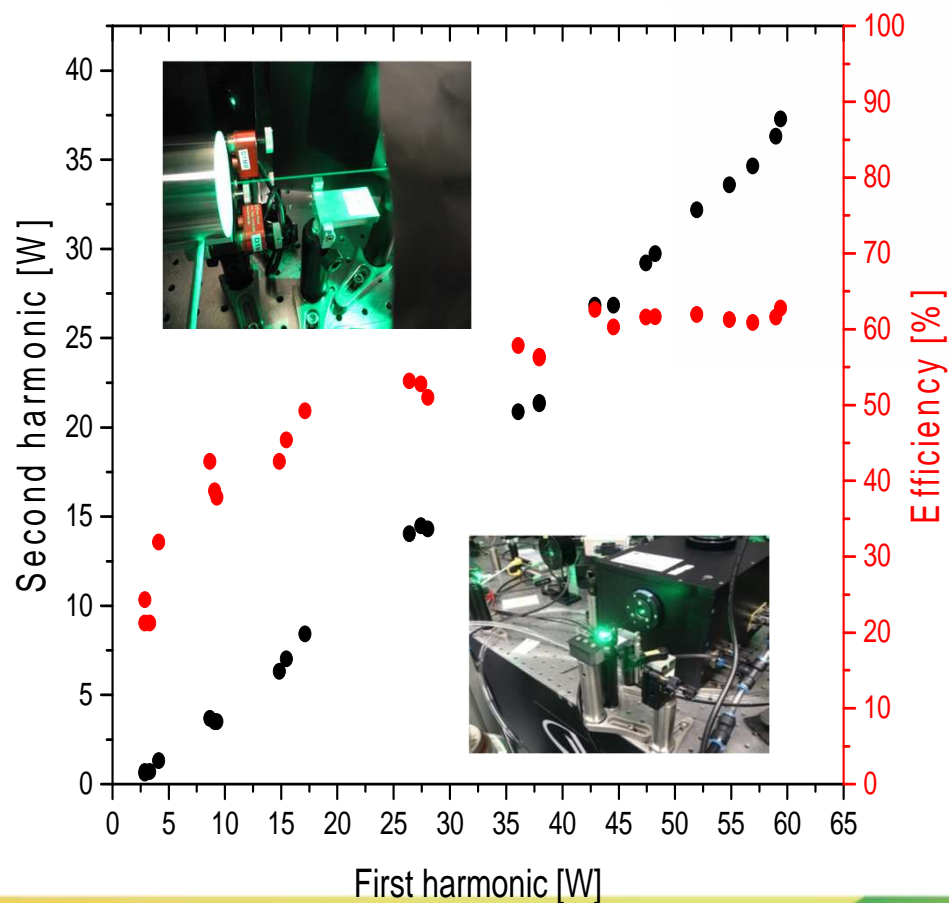


UV~DUV generation 4HG & 5HG ($1\omega + 4\omega$)

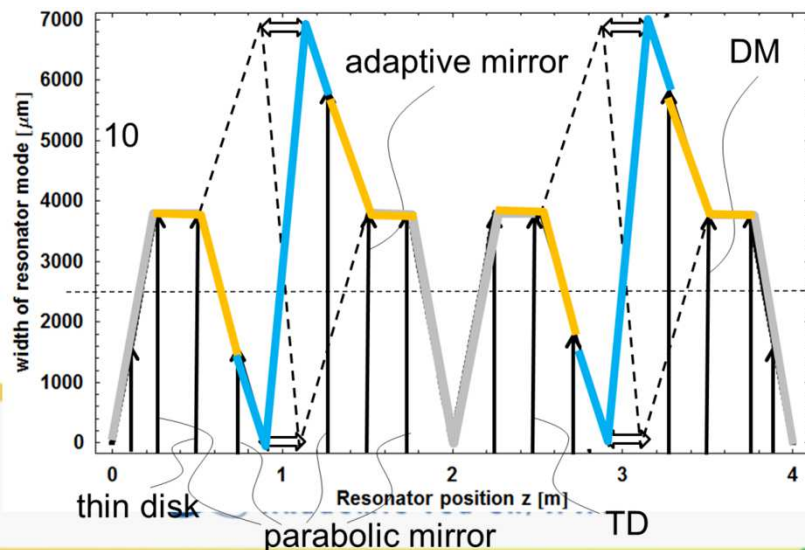
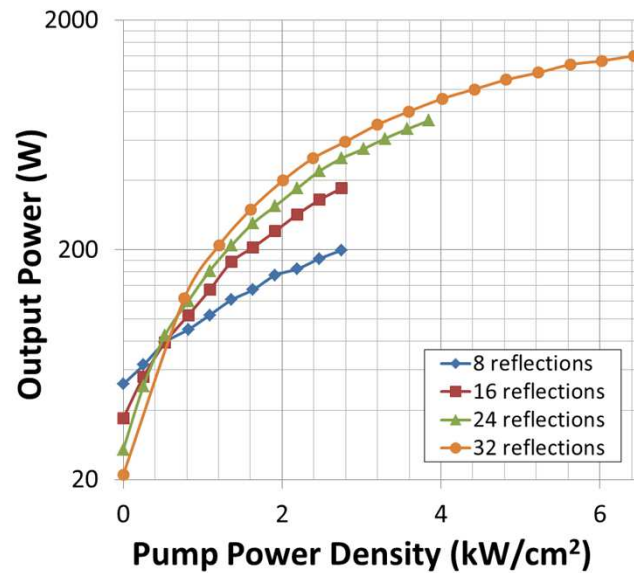


2nd and 4th harmonic generation

- 6 W in fourth harmonic (60 μ J, 1ps, 100kHz) reached !
paper submitted

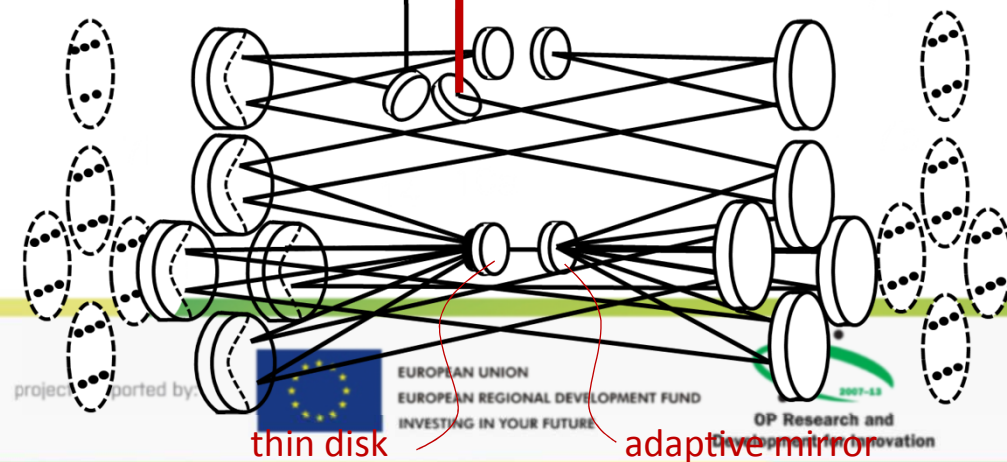
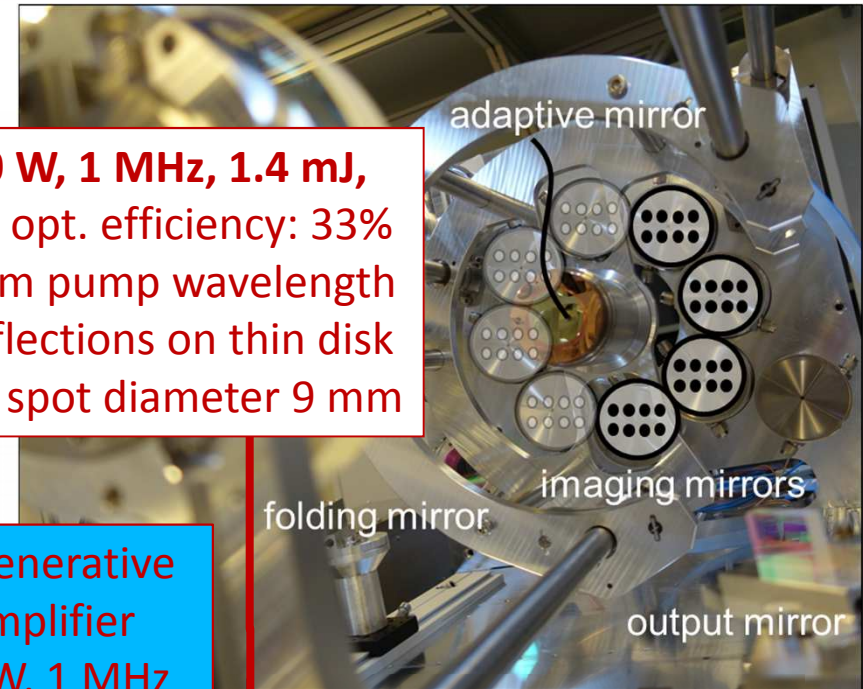


1.4 kW output operated at 1 MHz, multipass in air



1400 W, 1 MHz, 1.4 mJ,
opt. / opt. efficiency: 33%
940 nm pump wavelength
32 reflections on thin disk
pump spot diameter 9 mm

**Regenerative
amplifier
92 W, 1 MHz**



project supported by

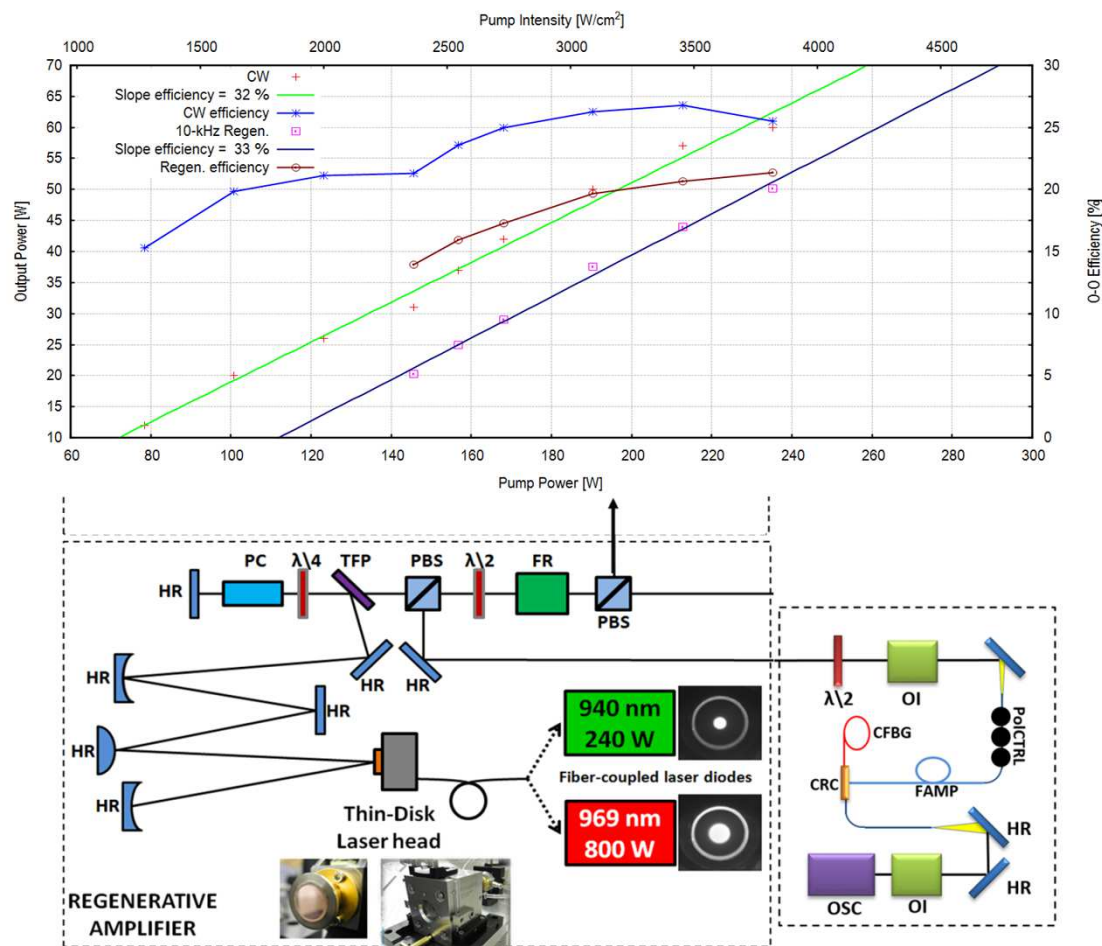
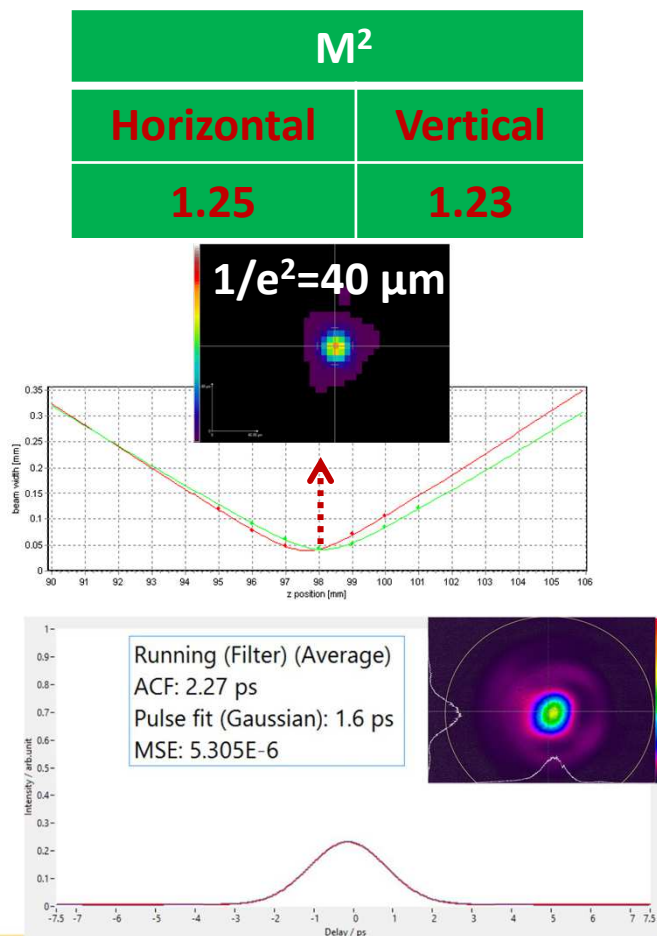


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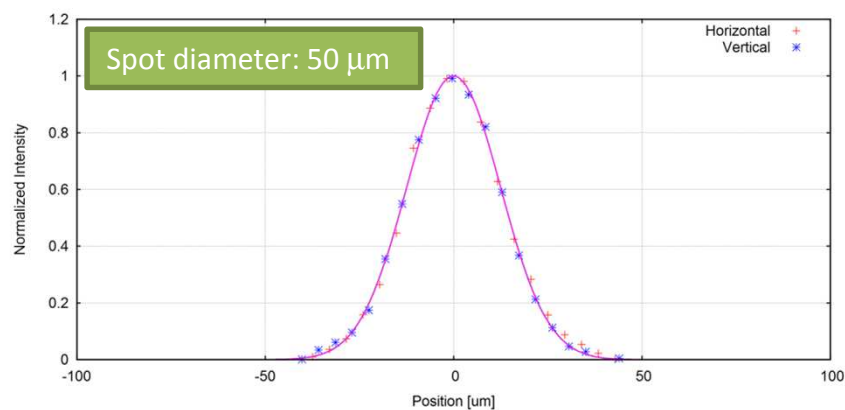
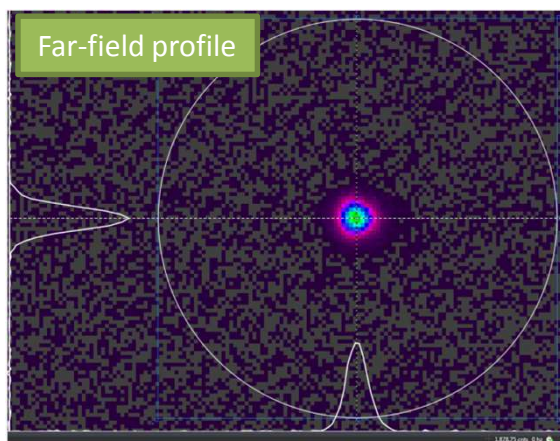
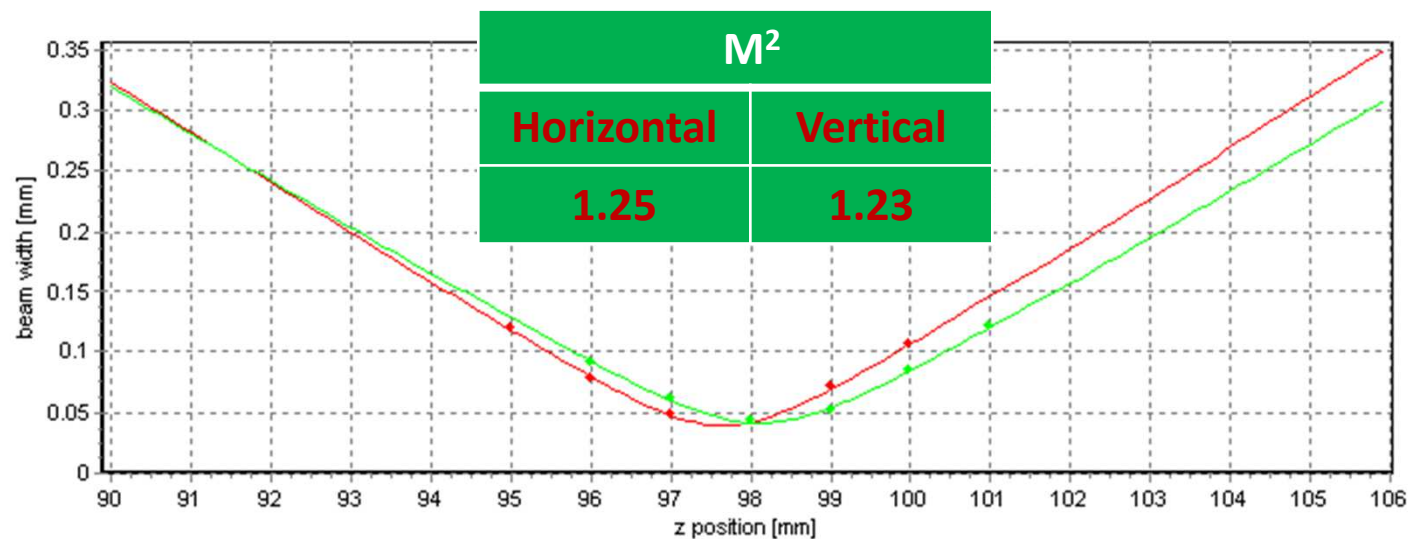
OP Research and
Development Innovation

High energy output obtained from HERA

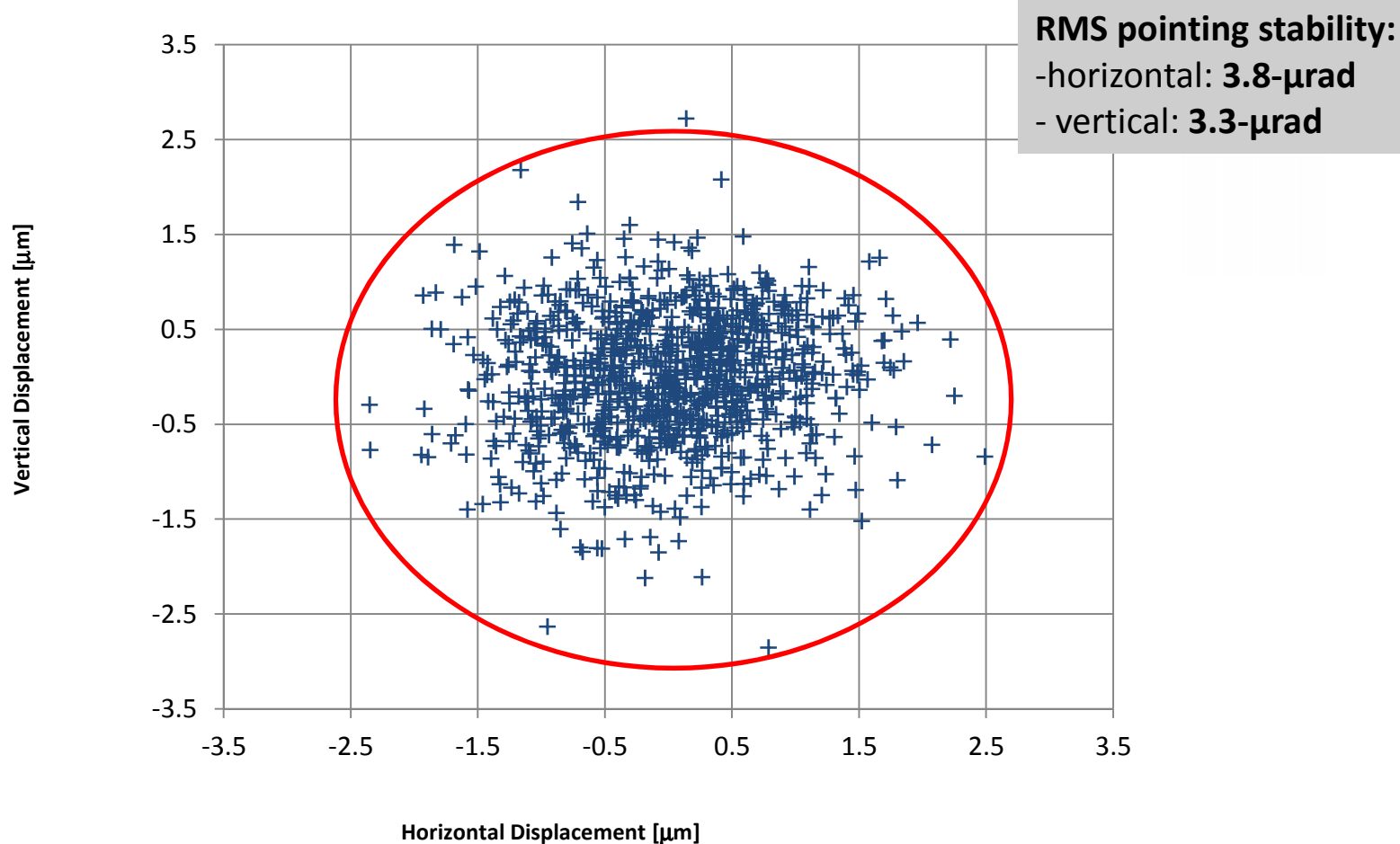
45 mJ at 1 kHz, 465 W@50%DC- 500 μ s at 969 nm, 20 % O-O eff.



M² measurement of HERA

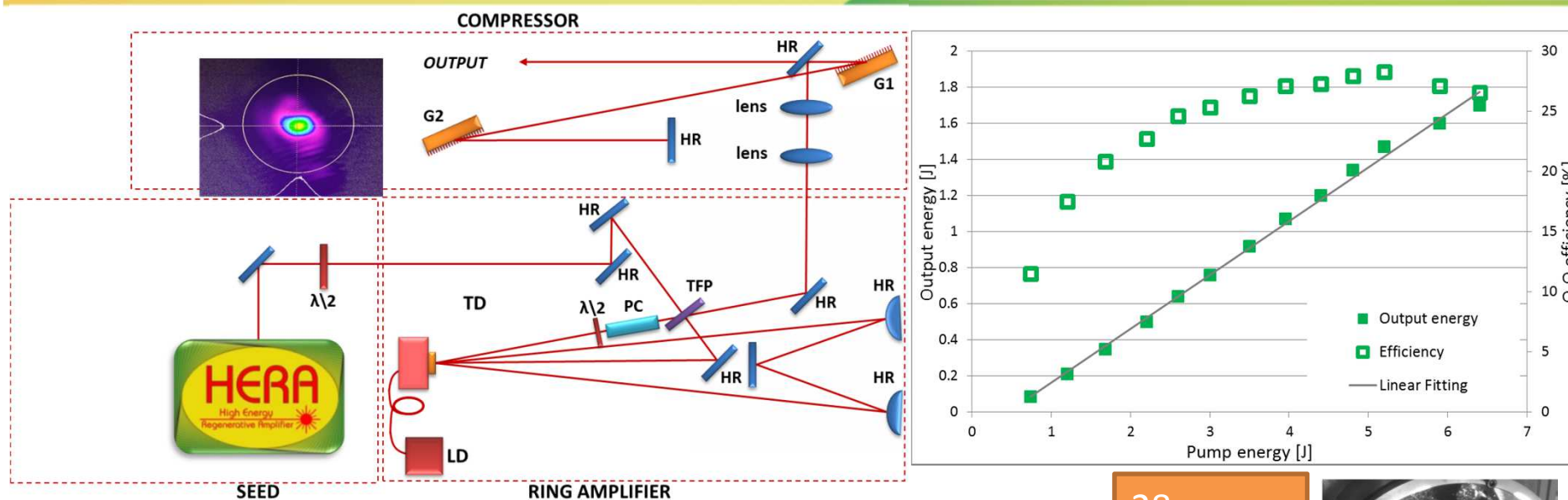


High beam pointing stability

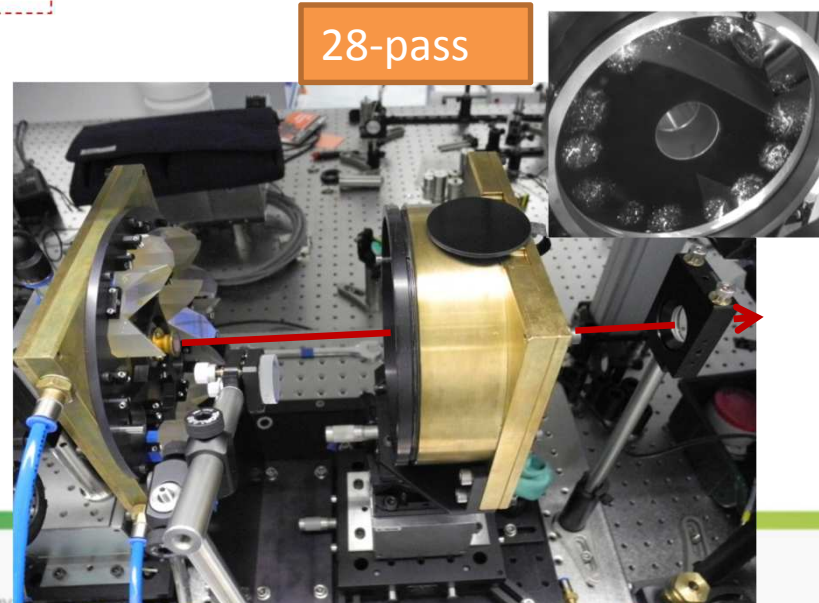


Measurement time: **15 min**

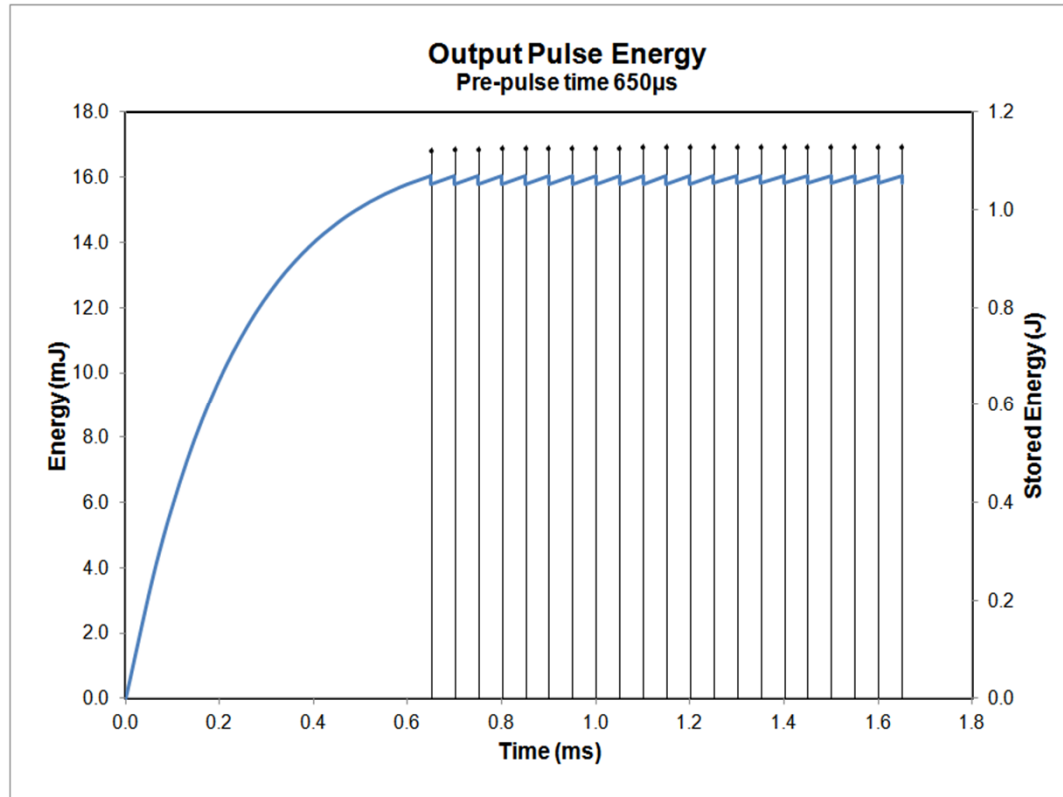
Over 1-J Output From HiLASE Thin Disk



28-pass



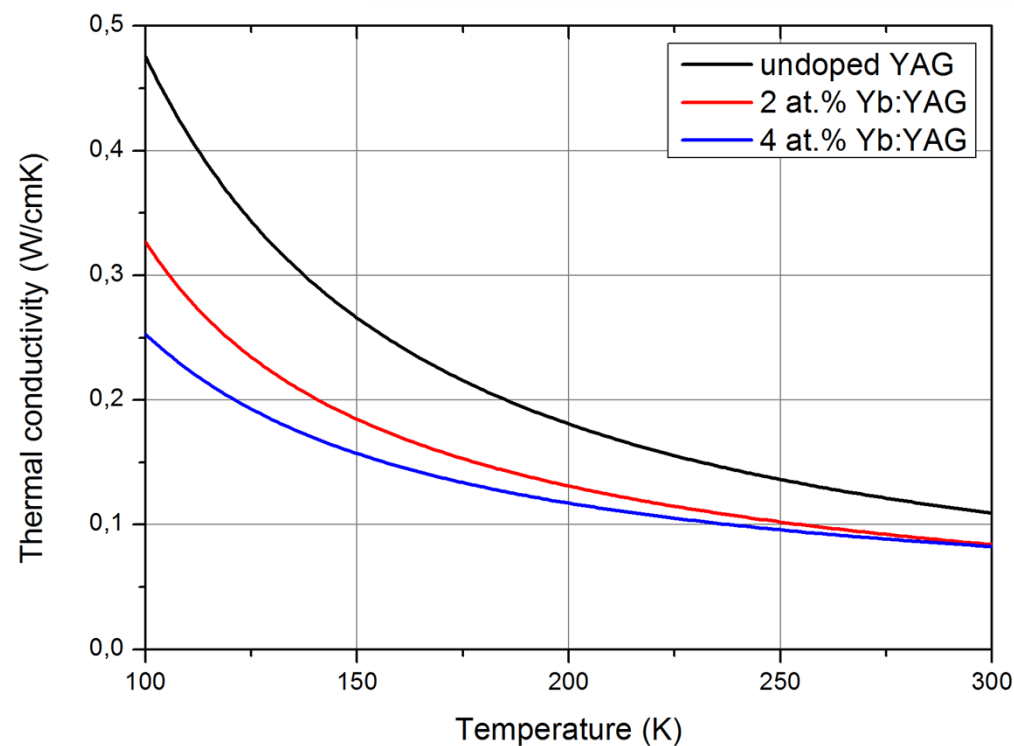
Yb:YAG as multi pulse amplifier for less ASE effect



1. Higher extraction efficiency
2. Minimize mirror distortion
3. $R = 10\mu\text{m}$ focus
4. Pointing stability $< \mu\text{m}$
5. No nonlinear Compton process

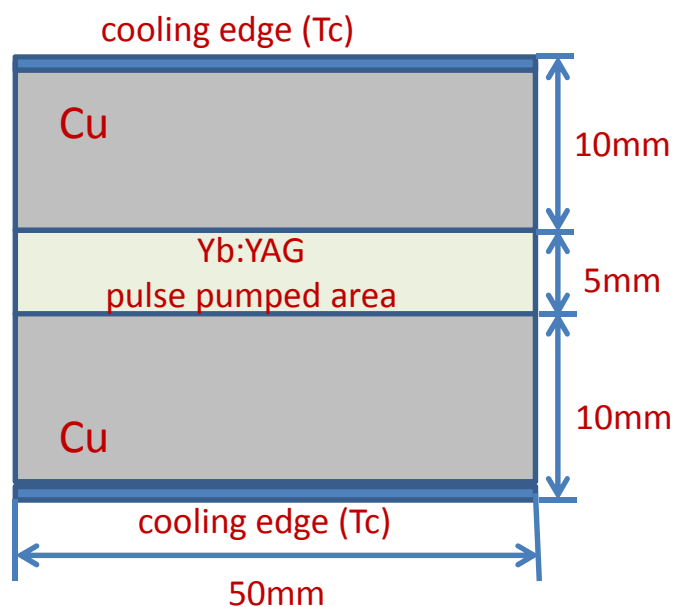
10J : 100mJ x 100 pulses, MHz (0.1ms bunch length)

Thermal conductivity as a function of temperature for Yb:YAG



Cryogenic laser : Model and Parameters

2D slab model



dimension of Yb:YAG: 50mm x 5mm x 20mm

dimension of Cu: 50mm x 10mm x 20mm

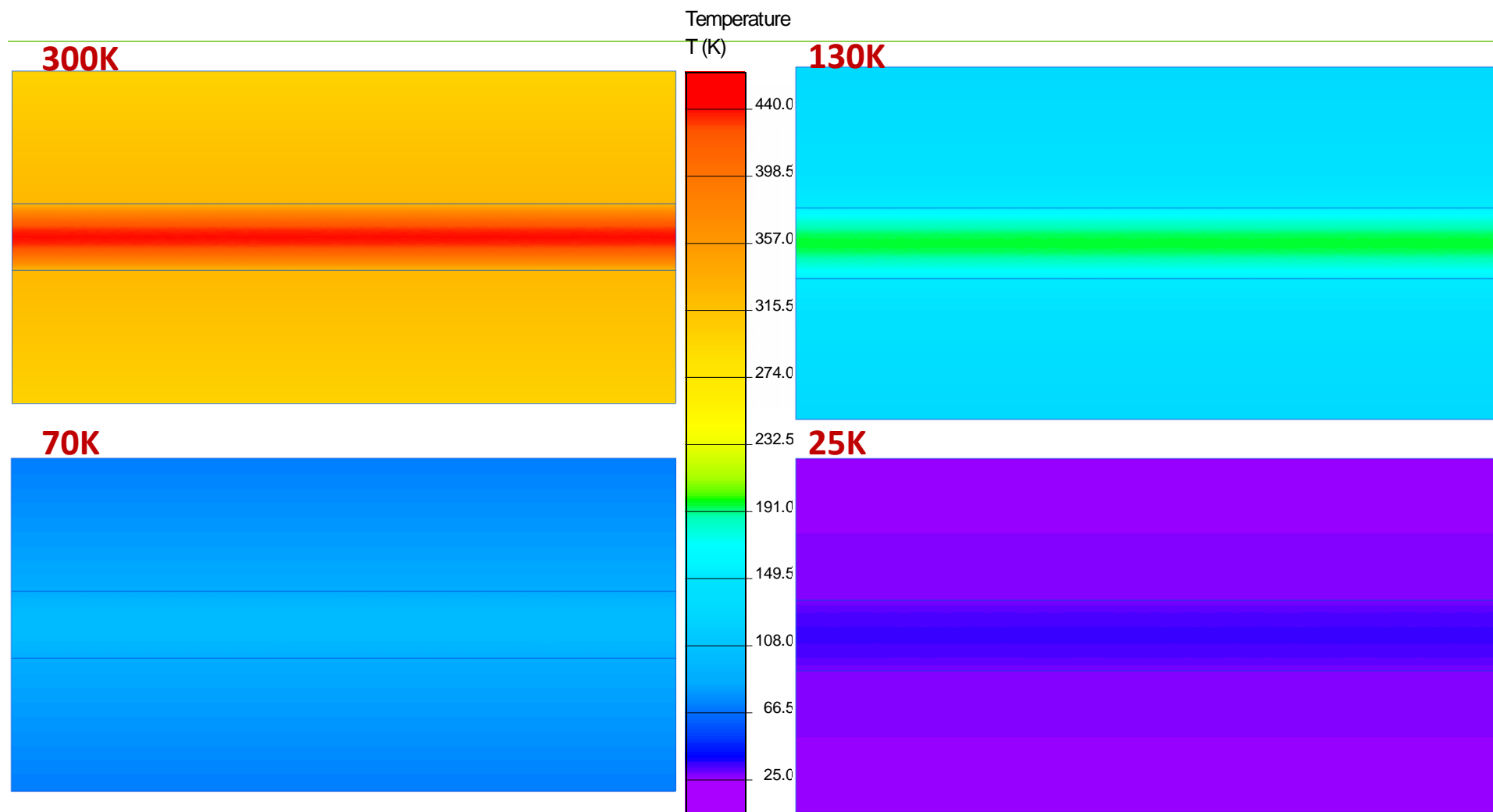
pump power transferred to heat – 4kW/cm²

pulse duration 1ms, frequency 100Hz

1% at concentration of Yb³⁺ in YAG

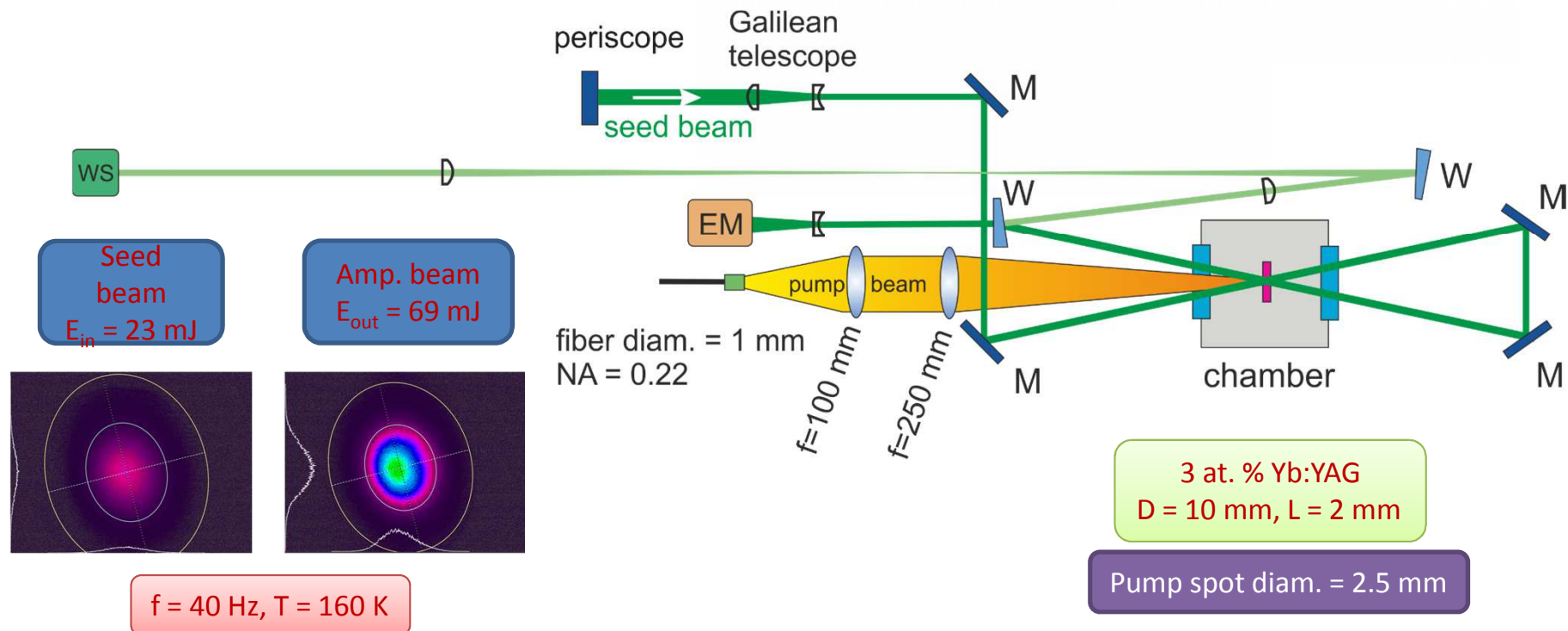
	Yb:YAG		Cu	
T_c [K]	thermal conductivity [W/mK]	specific heat [J/kgK]	thermal conductivity [W/mK]	specific heat [J/kgK]
300	11	625	401	390
130	30	250	450	300
70	95	150	647	170
25	600	100	7600	10

Results comparison – the same scale

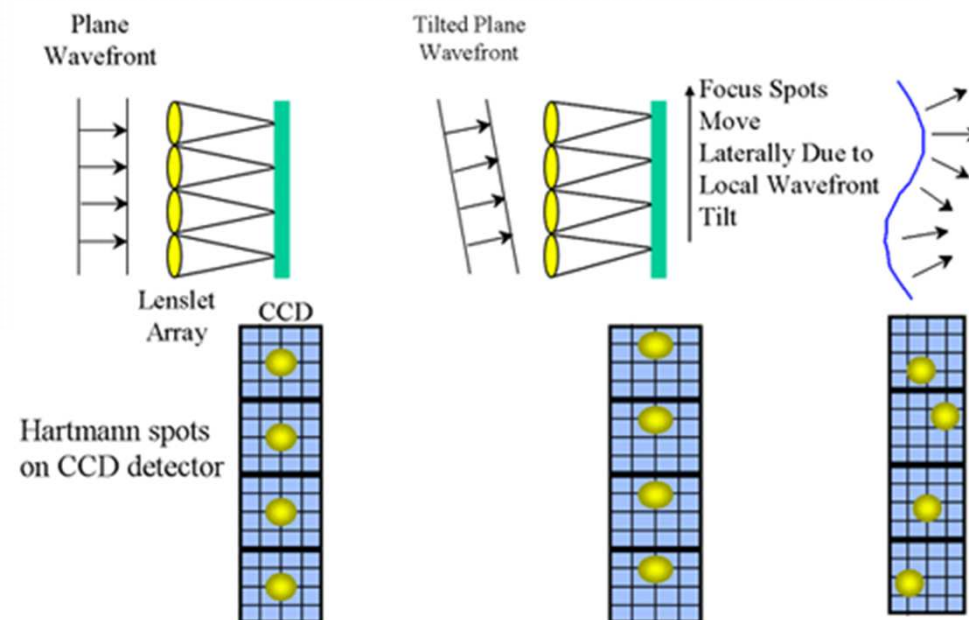
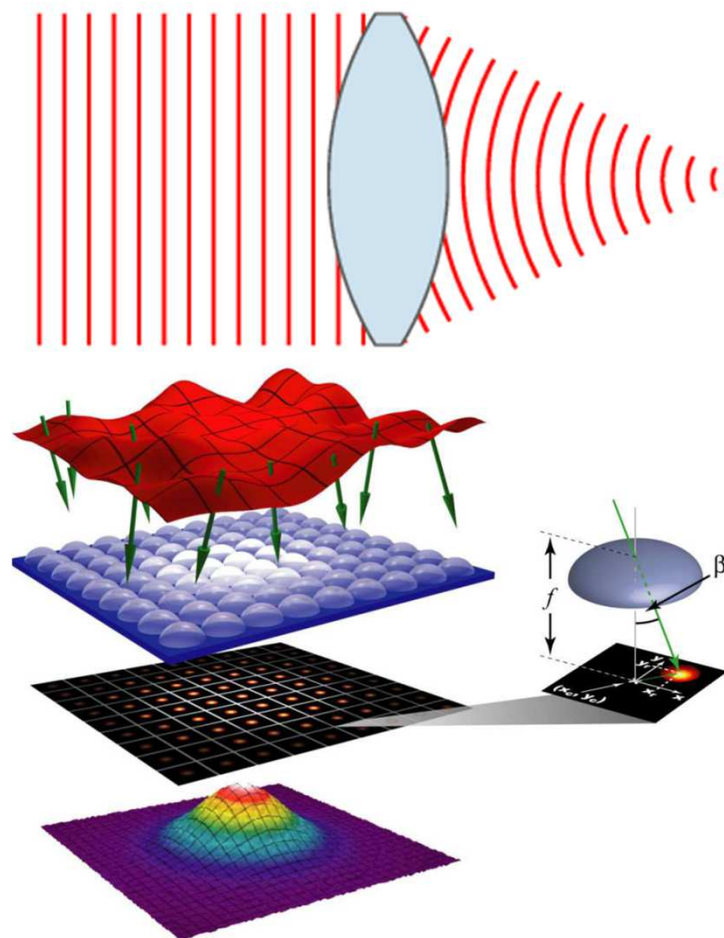


Setup for wavefront measurement of the amplified beam

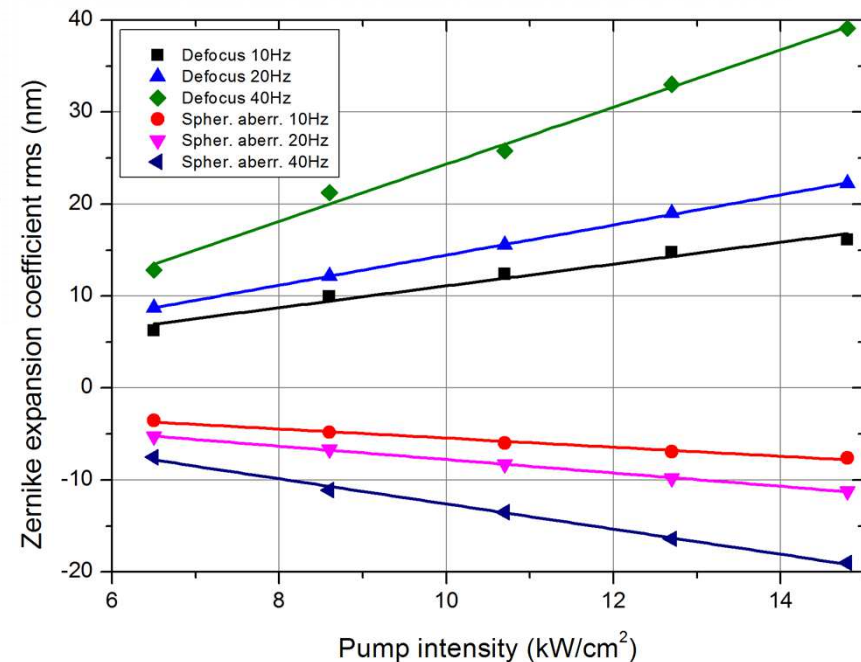
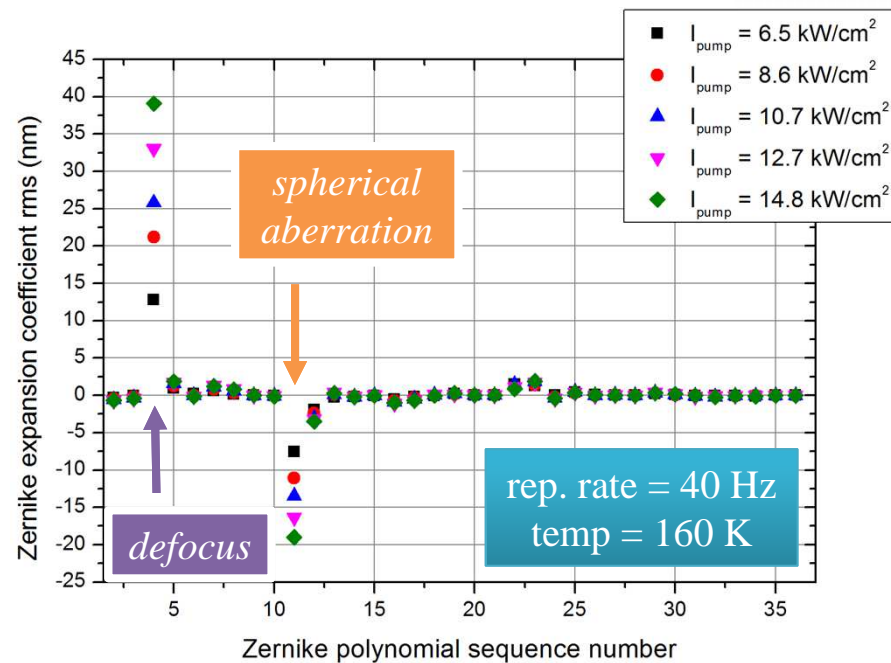
2 passes through the gain medium



Hartmann-Shack Wavefront Analysis

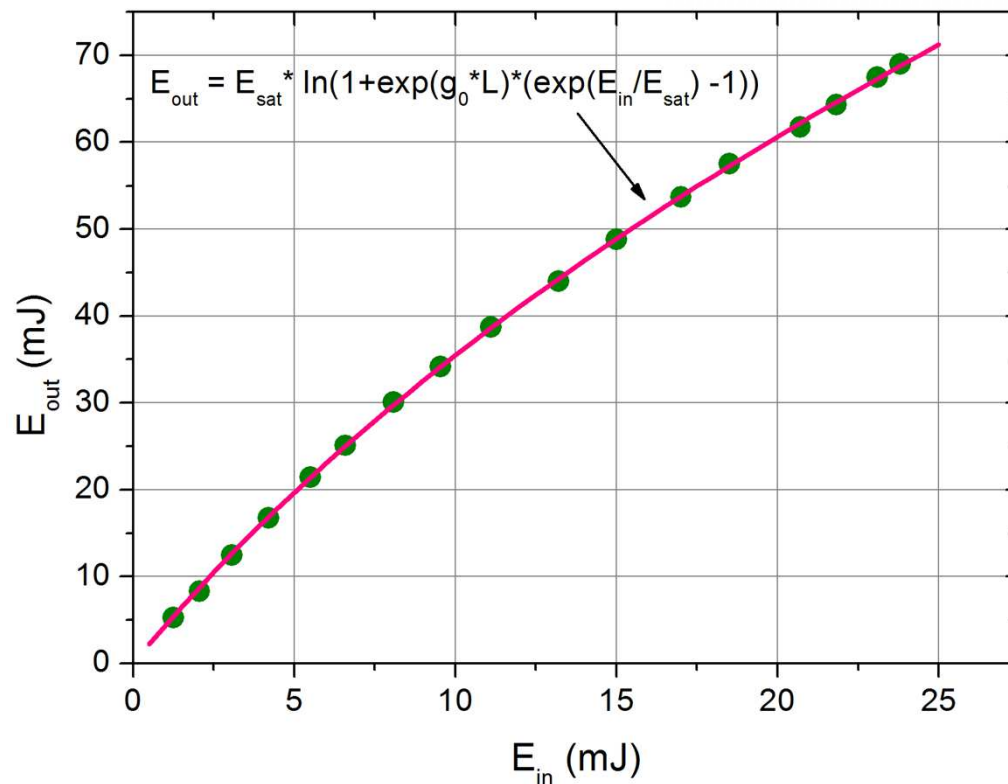


Net wavefront aberrations after 2 passes through cryogenically cooled Yb:YAG slab at different pump intensities



At $I_{\text{pump}} \sim 14.8$ kW/cm²
Spherical aberration is less than -20 nm
what corresponds to less than -0.02λ

Output energy vs input seed energy after 2 passes through the cryogenically cooled Yb:YAG slab



rep. rate = 40 Hz
temp = 160 K

$E_{sat} = 58$ mJ
 $g_0 = 7.5$ cm⁻¹

Conclusion and Perspective

- Picosecond $>mJ$, 100kHz ($>100W$) laser available for pre-pulse in LPP EUV source
- $>10kW$ EUV FEL needs advanced picosecond laser technology
10kW, $>10MHz$, picosecond laser for kW 3HG, 4HG, OPCPA
- Single shot bioimaging by laser Compton source possible by cryogenic J class high beam quality picosecond laser modules in multiplexing